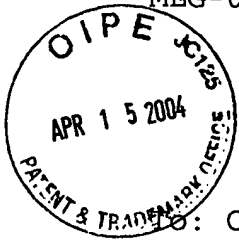


MEG-02-005



April 9, 2004

To: Commissioner for Patents  
P.O.Box 1450  
Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572  
28 Davis Avenue  
Poughkeepsie, N.Y. 12603

Subject: | Serial No. 10/786,807 02/25/04 |  
H.M. Chen et al.  
METHOD FOR IMPROVING SEMICONDUCTOR  
WAFER TEST ACCURACY  
| \_\_\_\_\_ |

#### INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation  
In An Application.

The following Patents and/or Publications are submitted to  
comply with the duty of disclosure under CFR 1.97-1.99 and  
37 CFR 1.56.

#### CERTIFICATE OF MAILING

I hereby certify that this correspondence is being  
deposited with the United States Postal Service as first class  
mail in an envelope addressed to: Commissioner for Patents,  
P.O. Box 1450, Alexandria, VA 22313-1450, on April 12, 2004.

Stephen B. Ackerman, Reg.# 37761

Signature/Date

 4/12/04

MEG-02-005

U.S. Patent 6,291,268 to Ho, "Low Cost Method of Testing a Cavity-Up BGA Substrate," discloses a method for testing a BGA substrate.

U.S. Patent 6,162,652 to Dass et al., "Process for Sort Testing C4 Bumped Wafers," describes a method of cleaning and testing bumped wafers.

U.S. Patent 6,143,668 to Dass et al., "KLXX Technology with Integrated Passivation Process, Probe Geometry and Probing Process," describes a wafer testing method utilizing cleaning of bond pads prior to testing.

Sincerely,

A handwritten signature in black ink, appearing to read 'SBA', with a long horizontal flourish extending to the right.

Stephen B. Ackerman,  
Reg. No. 37761

Form PTO-1449

Doc No (Number) (Cp Number)

Accession Number

MEG -02-005

10/786, 807

Logitcan!

H.M. Chen et al.

Filing Date: 11/11/2011

02/25/04

Group 1st Unit

## U. S. PATENT DOCUMENTS

[illegible]

## FOREIGN PATENT DOCUMENTS

[illegible]

## OTHER DOCUMENTS (Including Author, Title, Date, Portion(s) Pages, Etc.)

[illegible]

ΟΙ ΛΟΓΟΙ

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.